



Patent  
Attorney's Docket No. 015290-502

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of	)	
	)	
Helen H. ZHU et al.	)	Group Art Unit: 2823
	)	
Application No.: 09/820,694	)	Examiner: J. J. Maldonado
	)	
Filed: March 30, 2001	)	Confirmation No.: 7374
	)	
For: METHOD OF PLASMA ETCHING	)	
SILICON NITRIDE	)	

**AMENDMENT AFTER FINAL REJECTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed November 20, 2003, please amend the  
above-identified application as follows:

*do not  
enter  
02/27/2004  
ferr*